Appln. No.: 10/605,906

# IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): An L. STEEGEN et al. Confirmation No. 2905

Appln. No. : 10/605,906 Group Art Unit: 2813

Filed : November 5, 2003 Examiner: Stephen W. Smoot

For : METHOD AND STRUCTURE FOR FORMING STRAINED SI FOR

CMOS DEVICES

## SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
U.S. Patent and Trademark Office
Customer Service Window, Mail Stop Amendment
Randolph Building
401 Dulany Street
Alexandria VA 22314

#### Sir:

In accordance with the duty of disclosure under 37 C.F.R. § 1.56 and supplemental to the Information Disclosure Statements filed on filed on November 5, 2003, August 23, 2005 and February 9, 2005, applicant respectfully brings the following documents, listed on the attached form PTO-1449, to the attention of the Examiner in charge of the above-identified application.

Further to the U.S. Patent and Trademark Office's decision to waive the requirement under 37 C.F.R. § 1.98 (a)(2)(i), copies of the U.S. patents and U.S. published patent applications are not enclosed herewith. However, if any copies are needed, the Examiner is respectfully requested to contact the undersigned. Copies of the non-US patent documents as well as the documents listed in the "Other Documents" section of the attached PTO-1449 are enclosed.

Appin. No.: 10/605,906 (P27153 00027468 DOC)

Applicant respectfully requests that the Examiner consider the materials cited and indicate such consideration by appropriately initialing the enclosed PTO-1449 Form and including a copy of the initialed form in the next official communication.

Applicants note that this Information Disclosure Statement is being after receipt of a first action on the merits from the U.S. Patent and Trademark Office. Accordingly, Applicants are herein submitting the required fee, and authorization is hereby given to charge Deposit Account No. 09-0458 any fee necessary to ensure consideration of these materials.

Should there be any questions concerning this application, the Examiner is invited to contact the undersigned at the below listed telephone number.

Respectfully submitted, An L. STEEGEN et al.

Andrew M. Calderon Reg. No. 38.093

June 29, 2006 GREENBLUM & BERNSTEIN, P.L.C. 1950 Roland Clarke Place Reston, VA 20191 (703) 716-1191 U.S. Department of Commerce | Atty. Docket No.

Patent and Trademark Office

Application No. FIS920030236US1 10/605.906

INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)

Applicant An L. STEEGEN et al. Filing Date Groun 11/05/2003 2813

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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

EXAMINER

DATE CONSIDERED

\*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

FORM PTO-144		U.S. Department of Commerce Patent and Trademark Office MATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)			Atty. Docket No.			Application No.		
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